

Form PTO-1449 (MODIFIED)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. 039153-0447 (G1152)	SERIAL NO. <u>10/016439</u> <u>Unknown</u>
INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)		APPLICANT Lukanc et al.	
#2		FILING DATE <u>12/11/2001</u> <u>Unknown</u>	GROUP ART UNIT <u>Unknown</u> 754

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE IF APPROPRIATE
	A1	09/772,5277		Todd Lukanc			01/30/2001
NY	A2	6,228,539 B1	05/08/2001	Wang et al.	430	5	PRO
NY	A3	5,858,580	01/12/1999	Wang et al.	430	5	
NY	A4	5,807,649	09/15/1998	Liebmann et al.	430	5	
NY	A5	5,573,890	11/12/1996	Spence	430	311	

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION
							YES NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

NY	A6	Levenson et al., "Improving Resolution in Photolithography with a Phase-Shifting Mask," IEEE Transactions
		On Electron Devices, Vol. ED-29, No. 12, December 1982, pp. 1828-36.
NY	A7	Lin, B.J., "Phase-Shifting Masks Gain an Edge," Circuits & Devices, March 1993, pp. 28-35.

EXAMINER

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DATE CONSIDERED

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* EXAMINER: Initial if citation considered, whether or not citation is in compliance with MPEP 609; Draw line through citation if not in compliance and not considered. Include any copy of this form with next information.

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Substitute for form 1449B/PTO		Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Application Number	10/016,439
Date Submitted: May 24, 2002		Filing Date	12/11/2001
(use as many sheets as necessary)		First Named Inventor	Todd P. Lukanc
Sheet	1	Group Art Unit	1756
	of 1	Examiner Name	Unknown
		Attorney Docket Number	039153-0447 (G1152)

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS

OTHER PRIORITY NON-PATENT LITERATURE DOCUMENTS				
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.		T ⁶
	A5 ✓	Levenson et al., "Improving Resolution in Photolithography with a Phase-Shifting Mask," <u>IEEE Transactions on Electron Devices</u> , Vol. ED-29, No. 12, December 1982, pp. 1828-1836.		
	A6 ✓	Lin, B.J., "Phase-Shifting Masks Gain an Edge," <u>Circuits & Devices</u> , March 1993, pp. 28-35.		

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Standard ST.3). 4For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document.

5Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. **6**Applicant is to place a check mark here if English language Translation is attached.

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